

Serial No. 10/040017

1756B

IN THE UNITED STATES
PATENT AND TRADEMARK OFFICE

PATENT APPLICATION

Inventor(s): **Mischa Megens
Pierre Wiltzius
Shu Yang**

Case: **1-10-5**

Serial No.: **10/040017**

Filing Date: **January 4, 2002**

Examiner: **M. Angebrannt** Group Art Unit: **1756**

Title: **Fabricating Artificial Crystalline Structures**

COMMISSIONER FOR PATENTS
P.O. BOX 1450
ALEXANDRIA, VA 22313-1450
SIR:

INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR 1.97(c)(2)

In accordance with 37 CFR 1.97(c)(2), the enclosed Information Disclosure Statement, with attached reference(s), is submitted for consideration in the above-identified application.

Please charge the amount of \$180.00 to **Lucent Technologies Deposit Account No. 12-2325** to cover the fee under 37 CFR 1.17(p). Duplicate copies of this letter are enclosed.

05/04/2004 SDENB0B1 00000024 122325 10040017
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Respectfully,

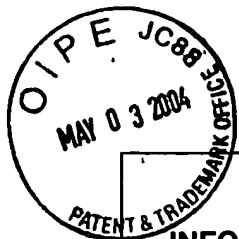
John F. McCabe

John F. McCabe, Attorney
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Date: April 29, 2004

Docket Administrator (Room 3J-219)
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INFORMATION DISCLOSURE STATEMENT	Case Name.	M. Megens 1-10-5
	Serial No.	10/040017
	Applicant:	M. Megens, et al.
	Filing Date:	January 4, 2002
	Group:	1756

U.S. PATENT DOCUMENTS

*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date

FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	Subclass	Translation

OTHER (including Author, Title, Date, Pertinent Pages, etc.)

	AA	Lee, K.Y., LaBianca, N., Rishton, S.A., Zolgharnain, S., Gelorme, J.D., Shaw, J., Chang, T.H.-P., <i>Micromachining Applications Of A High Resolution Ultrathick Photoresist</i> , J. Vac. Sci. Technol. B 13(6) Nov/Dec 1995, pp. 3012-3016.

***References listed beyond AZ would list as AA-1, AB-2, AC-3 thru AZ-26.

***Note First Page ONLY Header/Footer. Subsequent pages must ONLY have page # layout as header

EXAMINER	DATE CONSIDERED

***Examiner:** Initial if reference considered, whether or not citation is in conformance with MPEP 609: Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant